



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Chunyuan Chao, Kuei-Chang Tsai and George A. Kovall
Assignee: Mosel-Vitellic, Inc.
Title: Dynamically Controllable Reduction of Vertical Contact Diameter Through Adjustment of Etch Mask Stack for Dielectric Etch
Application No.: 10/718,320 Filing Date: 11/19/2003
Examiner: Deo, Duy Vu Nguyen Group Art Unit: 1765
Docket No.: M-15208 US Confirm No.: 1058

San Jose, California
October 19, 2006

Mail Stop RCE
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PETITION FOR EXTENSION OF TIME

Dear Sir:

Applicants respectfully petitions for a two-month extension of time within which to file the Response to the Office Action mailed on May 19, 2006 thus allowing the undersigned until October 19, 2006.

Please charge the amount of \$450.00 set forth in the enclosed transmittal letter.

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop RCE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on October 19, 2006.

 10-19-06
Attorney for Applicant(s) Date of Signature

Respectfully submitted,



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